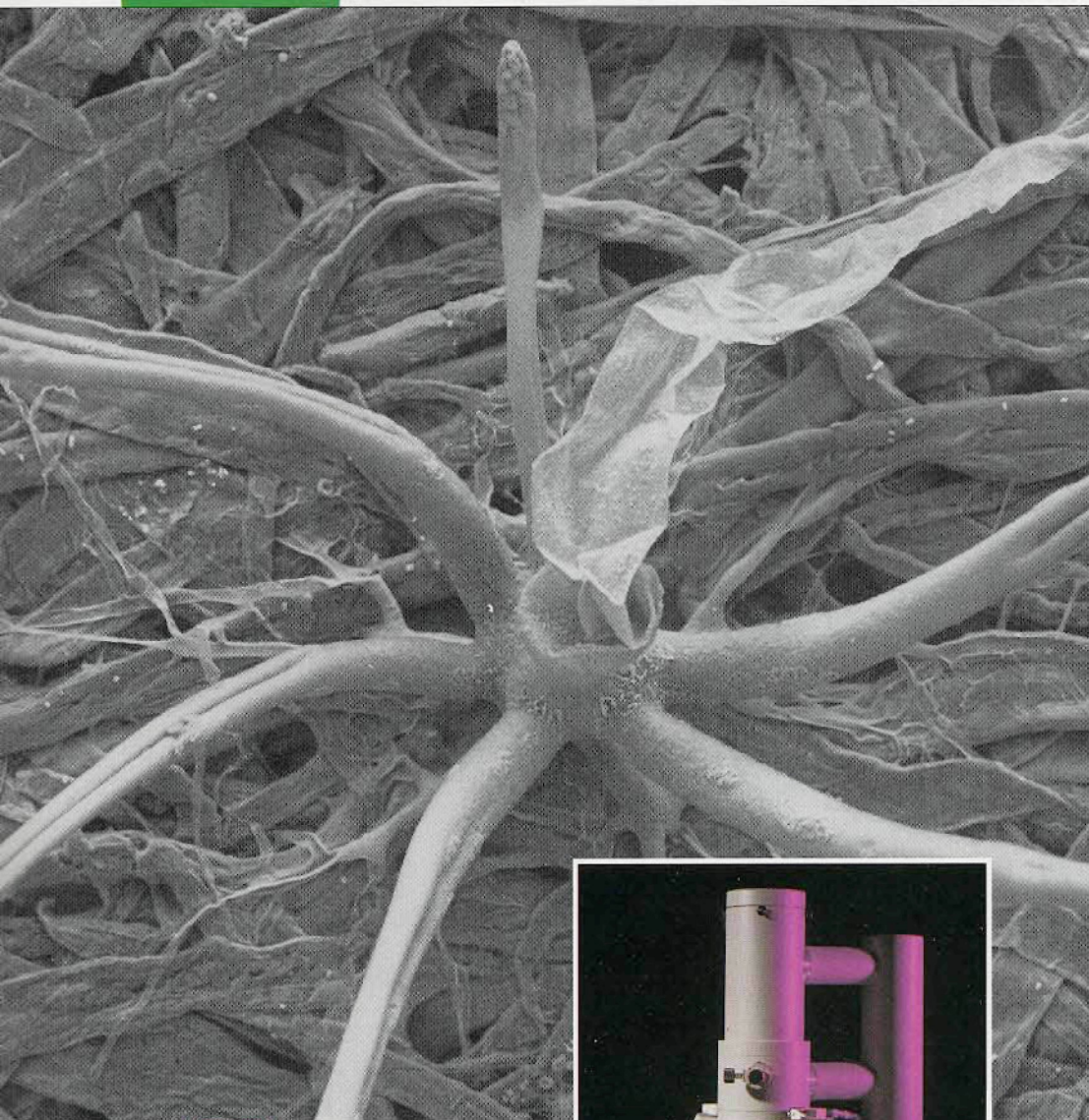# The pressure is on for new applications!

The LEO 435VP variable pressure scanning electron microscope opens up a whole new range of exciting possibilities.

With pressures up to 300Pa available, imaging and EDX analysis are now possible for out-gassing samples, non-conducting materials and hydrated specimens – all with little or no sample preparation.

In both variable pressure and high vacuum modes the LEO 435VP delivers stunning image performance and high resolution. Like other LEO 400 series models, it employs the most user-friendly microscope control interface on the market today, based on the intuitive Microsoft™ Windows® graphical environment.
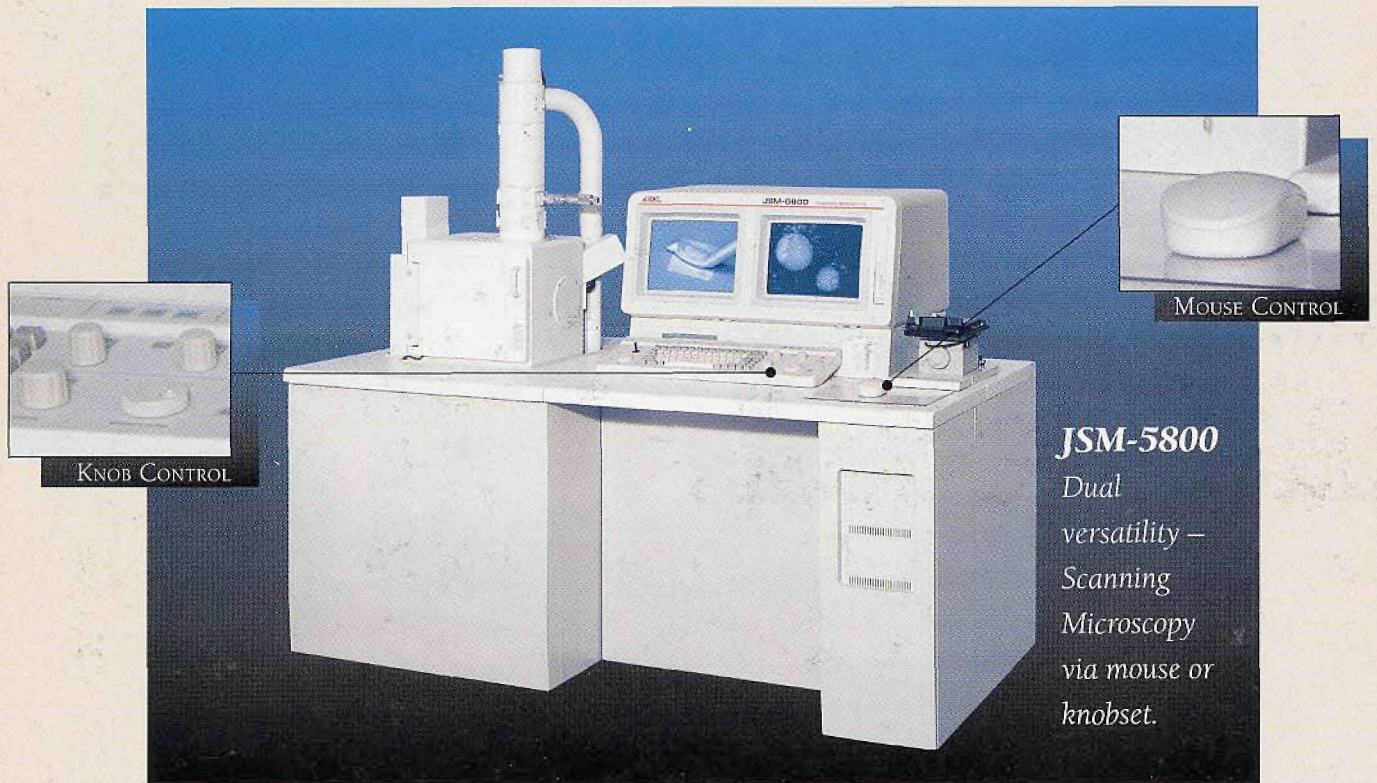
LEO - finding solutions through innovation.
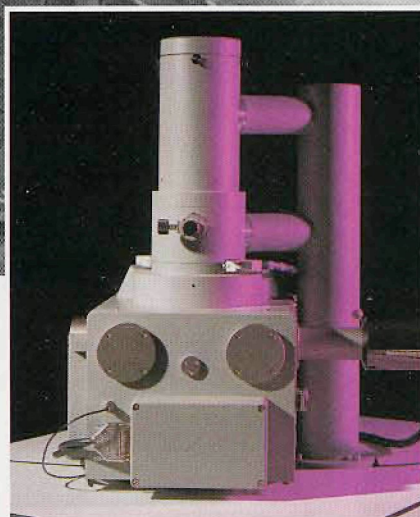
Co-operation Zeiss • Leica

LEO

Twice As Precise

JSM-5800 Scanning Microscope Features Two Options for Optimum Control.

KNOB CONTROL

MOUSE CONTROL

JSM-5800
Dual versatility — Scanning Microscopy via mouse or knobset.

■ *Large Specimen Stage* ■ *High/low vacuum capability* ■ *Super Conical Objective Lens for high resolution*

Suitable for a wide range of applications, the JSM-5800 from JEOL represents a new era in scanning microscopy. Now you have the option to choose either mouse or knobset control, while taking advantage of the super conical objective lens designed for the highest resolution (3.5nm) and large sample tilting.

▶ Easy-to-use unit has a wide range of built-in automatic functions.
▶ Large specimen stage allows room for up to an 8-inch sample.
▶ Archiving enables temporary or permanent storage and retrieval in standard TIF format.
▶ Five axis stage automation makes the JSM-5800 fast and easy-to-use.

Discover the twice as precise alternative that is as unique as your work itself.

To arrange for a demonstration of the innovative JSM-5800 call JEOL today.

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